

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-928001	Application No. 10/813,453
Information Disclosure Statement by Applicant <small>(Use several sheets if necessary)</small> <small>(37 CFR §1.98(b))</small>			
		Applicant Richard Schenker et al.	
		Filing Date March 29, 2004	Group Art Unit 2852

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						

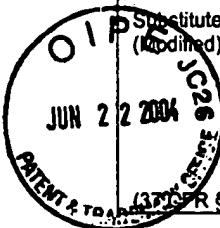
Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AI							
	AJ							
	AK							
	AL							
	AM							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
R	AN	Richard Schenker et al., "Material Limitations to 193-nm Lithographic System Lifetimes", SPIE Vol. 2726, pgs. 698-706
R	AO	Richard E. Schenker et al., "Ultraviolet-induced densification in fused silica", J. Appl. Phys. 82 (3), August 1, 1997, pgs. 1065-1071
R	AP	G. de Zwart et al., "Performance of a Step and Scan System for DUV Lithography", SPIE Vol. 3051, pgs. 817-830
	AQ	

Examiner Signature 	Date Considered 11/2/08
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-928001	Application No. 10/813,453
Information Disclosure Statement by Applicant (Use several sheets if necessary)		Applicant Richard Schenker et al.	
		Filing Date March 29, 2004	Group Art Unit

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications							
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation
							Yes No
	AL						
	AM						
	AN						
	AO						
	AP						

Other Documents (Include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
<i>PL</i>	AQ	Adam et al., "Polarization Effects in Immersion Lithography," Proc. of SPIE, Vol. 5377, pp. 329-342 (2004)
	AR	
	AS	
	AT	

Examiner Signature <i>AB JS</i>	Date Considered <i>11/12/05</i>
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	